

# Contents

<b>1</b>	<b>Introduction</b>	<b>1</b>
1.1	Short History: Classical Tools Versus Lasers Tools	2
1.2	Solid Materials (Metals, Semiconductors, Dielectrics) to be Processed by PLA	6
1.2.1	Thermally Well-Conducting Materials	7
1.2.2	Wide-Bandgap Materials, Glasses, Polymers	8
1.3	Practical Applications of PLA and General Aims	8
1.3.1	PLD	8
1.3.2	Cluster Formation by PLA	9
	References	11
<b>2</b>	<b>Lasers for Pulsed Laser Ablation</b>	<b>15</b>
2.1	CO <sub>2</sub> , Nd-YAG, Ti-Sapphire, Excimers Lasers	15
2.1.1	Nd-YAG Laser	17
2.1.2	Ti-Sapphire Laser	20
2.1.3	Excimer Laser	22
2.1.4	CO <sub>2</sub> Laser	23
2.2	Nano, Pico, Femtosecond Lasers, Q-Switched and Mode Locked Lasers	25
2.2.1	Nano, Pico, Femtosecond Lasers	25
2.2.2	Q-Switched and Mode Locked Lasers	28
2.3	Laser Parameters to be Controlled in PLA for Different Types of Solid Materials in Different Ambient Conditions	39
2.4	Basic Experimental Setup for PLA	44
2.4.1	Combined Irradiation Methods	46
2.4.2	Projection Through Microlens Array	47
2.4.3	Laser Trepanning	48
	References	49

<b>3</b>	<b>Laser-Matter Interaction Below the Plasma Ignition Threshold Intensity</b>	<b>53</b>
3.1	Linear and Non-linear Phenomena Involved in Laser-Matter Interaction at High Intensities: Harmonic Generation, Self Focusing, Self Guiding, Absorption and Ionization	54
3.1.1	Second Order Nonlinear Effects	54
3.1.2	Third-Order Nonlinear Effects	56
3.1.3	Photoionization	60
3.2	Experimental Methods for Analyzing the Main Phenomena Involved in Laser-Matter Interaction During PLA Below the Plasma Ignition Threshold: Reflectometry, Analysis of Thermal Radiation	61
3.3	Theoretical Models for PLA Below the Plasma Ignition Threshold	65
3.3.1	Semi-Quantitative Analytical Models	67
3.3.2	Numerical Photo-Thermal Models for Short Laser Pulses	71
	References	74
<b>4</b>	<b>Laser-Matter Interaction Above the Plasma Ignition Threshold Intensity</b>	<b>77</b>
4.1	Main Phenomena Involved in Production of the Ablation Plasma and in Laser-Plasma Interaction During PLA: Plasma Formation and Evolution	78
4.1.1	Plasma Heating, Self Focusing, Critical Density, Shielding	80
4.1.2	Ablation Plume Expansion	82
4.1.3	Interaction of Plasma Plume with Obstacles	93
4.2	Experimental Methods for Analyzing the Main Phenomena Involved in Laser-Plasma Interaction: Optical and Mass Spectroscopy, High Speed Imaging	95
4.2.1	Interferometric Methods	96
4.2.2	Thomson-Scattering	104
4.2.3	Spectrometric Methods	112
4.2.4	Laser Induce Fluorescence (LIF) Spectroscopy	119
4.2.5	Mass Spectrometry (MS)	123
4.3	Theoretical Models for Plasma Mediated PLA	129
4.3.1	Numerical Photo-Thermal Models	129
4.3.2	Numerical Photo-Thermal-Hydrodynamical Models for Plume Expansion and Material Removal	136
	References	138

<b>5</b>	<b>Material Removal and Deposition by Pulsed Laser Ablation and Associated Phenomena . . . . .</b>	<b>143</b>
5.1	Micro and Nano Processing (Patterning) of Materials by PLA . . . . .	143
5.1.1	Irradiation in Non-reactive Atmosphere . . . . .	145
5.1.2	PLA in Gaseous and Liquid Etching Medium . . . . .	151
5.2	Nanoparticles Production . . . . .	157
5.2.1	Nanoparticles Growing Mechanism . . . . .	157
5.2.2	Parameter Control . . . . .	158
5.2.3	Limitations . . . . .	160
5.3	Pulsed Laser Deposition . . . . .	160
5.3.1	Ablation . . . . .	162
5.3.2	Propagation . . . . .	164
5.3.3	Deposition . . . . .	165
5.3.4	Plume Filtering . . . . .	165
5.3.5	Shutter Technique . . . . .	167
5.3.6	Geometrical Techniques . . . . .	170
5.3.7	Axe-off Deposition . . . . .	171
5.3.8	Back-Side Deposition . . . . .	173
5.3.9	Plane Mask Technique . . . . .	175
5.3.10	Multiple Element Masks Filtering . . . . .	181
5.3.11	Helical Mask . . . . .	184
5.3.12	Plume Reflection Technique . . . . .	188
5.4	Harmonics Generation in Solids, Liquids and Gases . . . . .	193
5.4.1	Low-Order Harmonics Generation . . . . .	193
5.4.2	High Harmonics Generation from Solid Density Plasmas . . . . .	199
5.4.3	Coherent Wake Emission Harmonics . . . . .	204
5.4.4	Relativistic Oscillating Mirror Harmonics . . . . .	206
	References . . . . .	210
<b>6</b>	<b>Experimental Techniques for Analyzing the Material Removal and Deposition Rates in Real Time . . . . .</b>	<b>215</b>
6.1	Optoacoustics and Interferometric Methods for Real Time Monitorization of the Ablation Rates and Dimensions of the Ablated Structures . . . . .	215
6.2	Spectroscopy of the Ablation Plasma as a Real Time Monitor for the Ablation Rates and the Dimensions of the Ablated Structures . . . . .	219
6.3	Microbalances for Real Time Monitor of the Ablation and Deposition Rate . . . . .	221
	References . . . . .	224

<b>7 Conclusion</b> .....	225
References .....	229
<b>Subject Index</b> .....	231